

Mechanically Compliant Single-Path and Multi-Path Electrical Interconnects

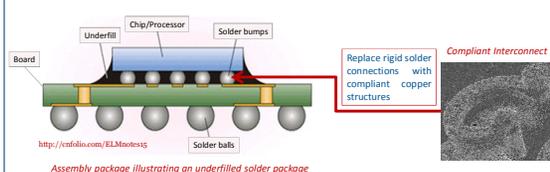
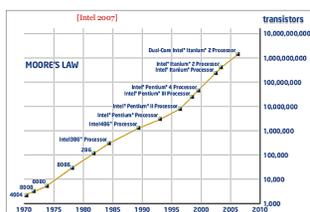
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Background

Moore's law states that the number of transistors on a chip will double approximately every two years.

Microprocessor development has followed this trend leading to more communications within a given chip size.

To accommodate the increased communications between the chip and motherboard, Input/Output (I/O) port sizes on the chip continue to be scaled down to increase their count over a given chip area.



For high performance chips, solder balls have typically been the interconnection of choice linking the chip's I/Os with the motherboard's. However, due to the scale down in size of the I/Os and solder balls, coupled with the coefficient of thermal expansion mismatch between the chip and motherboard, solder balls by themselves can no longer reliably attach the chip to the board. Hence prompting the development of new technology, *compliant interconnects*.

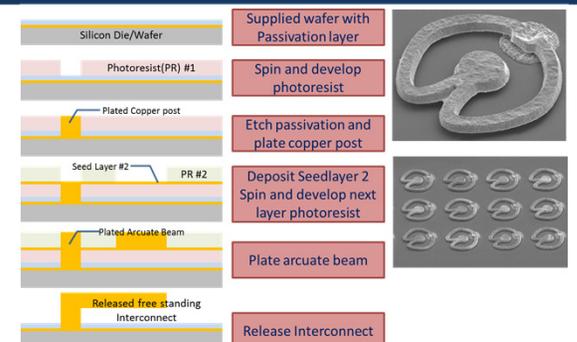
Research Objectives

- Enhance mechanical compliance
 - 7 mm/N to reduce die stresses/prevent low-k cracking
 - Improve Copper interconnect fatigue live to ~1000 cycles
- Improved electrical performance
 - Lower electrical resistance
 - Lower self and mutual Inductance
- Cost effective solution
 - Batch fabrication
 - Reduced number of fabrication steps
 - Compatible with current industry practices
- Vibration Analysis
 - Understand behavior of Compliant Interconnect assemblies under Shock and Impact loads

Highlights of Select Designs

| | | | |
|--|---|--|---|
| | J-Springs [Ma et al, 2002] Ultra-fine density High compliance Non-standard fab process High contact resistance | | G-Helix [Zhu et al, 2004] High Compliance Batch Fabrication High electrical parasitics Moderately costly fabrication |
| | Sea of Leads [Bakir et al, '03] No underfill Batch Fabrication Limited compliance Electroplated gold | | ELASTec [Dudek et al, 2006] No underfill Batch fabrication Limited Compliance Limited Pitch |
| | Beta-Helix [Zhu et al, 2004] High compliance Batch Fabrication Costly fabrication High electrical parasitics | | Flex Connect [Kacker, 2008] High compliance High compliance Good electrical parasitics Relatively low cost fabrication |

Fabrication



Performance Comparison

Fatigue life characterization of interconnects is based on a Coffin-Manson type equation using plastic strain range as failure metric.

$$N_f^{-0.6} \times \epsilon_f^{0.75} = \Delta \epsilon_p$$

*Coefficients are representative for annealed copper
 ϵ_f - fatigue ductility coefficient, $\Delta \epsilon_p$ - plastic strain range, N_f - fatigue life

Failure in all cases was observed in the copper interconnect structures. These packages were not underfilled by design.

| | Resistance [m-Ohm] | Inductance [pH] | Compliance [mm/N] | Fatigue life [cycles] |
|-------------|--------------------|-----------------|-------------------|-----------------------|
| J-Springs | ∞ | NA | 10000 | NA |
| Sea of Lead | NA | NA | 0.91 | NA |
| Beta Helix | 51.4 | 102 | 11.1 | >3000 |
| G-Helix | 42.7 | 92.7 | 11.5 | 3118 |
| Flex | 40.9 | 36.5 | 6.47 | ~1000 |
| Multi-path | 37 | 37 | ~3 | >1000 |

Impact Analysis: Board-Level Drop Test

- Board-level drop test simulation was conducted to understand response under Impact loading
- Simulation results for board deflection agree with published data and analytical calculation
- This approach will be extended to Impact Testing of Compliant Interconnects and validated against experimental data

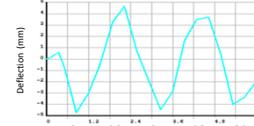
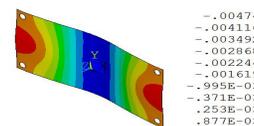
Comparison of Deflection Results

| | Deflection (mm) | Stress, SX (MPa) | Strain (µstrain) |
|------------------------|-----------------|------------------|------------------|
| Input G simulation | 5.21864 | 355.956 | 21738.6 |
| Analytical Calculation | 5.1579 | 357 | 22300 |
| Error (%) | 1.1639 | 0.2932 | 2.5825 |

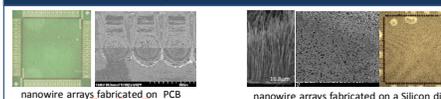
Converting Acceleration to Displacement (Input-G Method):

$$d(t) = \int_0^t \int_0^t G(\tau) d\tau d\tau$$

$$d(t) = \int_0^t G(\tau) d\tau = \int_0^t G_m \tau d\tau = \frac{1}{2} G_m t^2$$



Compliant Nanowire Z-axis Interconnect



• Very strong bond between Nanowires & substrate

• Highly compliant due to the very high aspect ratio of the nanowires,

- Low temperature assembly is possible due to the depressed melting-point of nanowires
- "Velcro-like" bonding has larger contact surface compared to planar contact
- Solder free assemblies are possible.

Multi-path Designs



Multi-path Compliant Interconnects

- Design targeted at obtaining suitable compromise between electrical and mechanical properties
- Symmetric design allows for uniform in plane compliance
- Multi-path also diminishes effects of electrical parasitics
- Domed variation may find use for probing applications
- May also find application as micro-vibration absorbers